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Information Disclosure Citation in an Application		Docket Number 004578.1148		Dipankar (nmi) Chandra, et al.	
				Group Art Unit	Filing Date

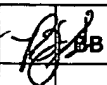

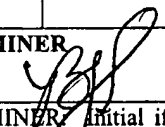
U.S. PATENT DOCUMENTS							
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↓	A	4,549,427	10/29/85	Kolesar, Jr.	73	23	9/19/83
	B	4,809,552	3/7/89	Johnson	73	517	11/23/87
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		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
↓	O	1252433	11/3/71	GB	G01P	5/04		
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NON-PATENT DOCUMENTS		
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	W International Search Report for PCT/US99/30661	4/17/00
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		9/29/2003	
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